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Serial Number: **10/823,199**

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 **PALM INTRANET**

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1	US 7098087 B2	20060829	Manufacturing method of semiconductor device	438/151	438/149; 438/164; 438/788; 438/792	Akimoto; Kengo et al.
1	US 7087885 B1	20060808	Particle size distribution measuring apparatus and method	250/222.2	356/336	Yamaguchi; Tetsuji
1	US 7042557 B2	20060509	Sample supplying device for a dry particle-size distribution measuring apparatus and method	356/36	221/180; 356/336	Yamaguchi; Tetsuji et al.
1	US 7021194 B2	20060404	Sliding component and compressor	92/71		Shimo; Toshihisa et al.
1	US 7009021 B2	20060307	Paint composition, proces for producing wear- resistant coating film using the same, and wear- resistant coating film comprising the same	528/10	428/412; 428/446; 528/15; 528/17; 528/18	Tani; Masaaki et al.
1	US 6988875 B2	20060124	Lubricating structure in fixed displacement piston type compressor	417/269	184/6.17; 92/12.2	Shintoku; Noriyuki et al.
1	US 6971639 B2	20051206	Orifice devices with lock mechanisms, vibration absorption devices having the orifice devices, and methods of assembling the	267/140.13	29/240	Okada; Hiroki et al.

			orifice devices			
1	US 6864979 B2	20050308	Particle size distribution measuring apparatus	356/336	356/338	Yamaguchi; Tetsuji
1	US 6862975 B2	20050308	Apparatus for lubricating piston type compressor	92/154	92/156; 92/71	Shintoku; Noriyuki et al.
1	US 6855768 B2	20050215	Coating composition, coating method, and coated article	525/100	106/287.11; 525/102	Matsumura; Kazuyuki et al.
1	US 6838509 B2	20050104	Phenolic resin composite material	524/447	524/425; 524/445; 524/449; 524/493; 524/494	Shimo; Toshihisa et al.
1	US 6837691 B2	20050104	Refrigeration suction mechanism for a piston type compressor and a piston type compressor	417/269		Tarutani; Tomoji et al.
1	US 6773001 B2	20040810	Vibration isolation mount	267/140.4	267/294	Saiki; Akio et al.
1	US 6766811 B2	20040727	Method of removing smear from via holes	134/1.3	216/13; 216/17; 216/18; 216/57; 216/65; 438/704; 438/708; 438/725	Shimo; Toshihisa et al.
1	US 6755401 B2	20040629	Fluid-filled vibration damping device	267/140.11	267/140.13	Akasa; Shouji et al.
1	US 6744507 B2	20040601	Dry particle distribution measuring apparatus and method	356/336		Yamaguchi; Tetsuji
1	US	20040224	Swash plate type	92/71	228/115	Kato;

	6694864 B2		compressor			Takayuki et al.
1	US 6677047 B2	20040113	Coating composition, coating method, and coated article	428/447	106/287.11; 526/279; 528/38	Matsumura; Kazuyuki et al.
1	US D483756 S	20031216	Operation controller for electronic computers	D14/356		Tanaka; Keita et al.
1	US D479235 S	20030902	Portable information terminal	D14/346		Tanaka; Keita et al.
1	US D479234 S	20030902	Portable information terminal	D14/346		Tanaka; Keita et al.
1	US 6589021 B2	20030708	Single-headed piston type swash plate compressor	417/222.2	92/71	Kato; Takayuki et al.
1	US 6568918 B2	20030527	Lubrication coating for the sliding portion of a swashplate compressor	417/269	184/6.17; 417/222.2; 92/155; 92/71	Sugioka; Takahiro et al.
1	US D474184 S	20030506	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki et al.
1	US D473875 S	20030429	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki et al.
1	US D473874 S	20030429	Optical disk cartridge	D14/435		Taniguchi; Toshiyuki et al.
1	US 6538051 B1	20030325	Aqueous coating agent of hydrophilic resin, MoS ₂ and Sb ₂ S ₃ and/or Sb ₂ S ₅	523/402	524/560; 524/588; 524/601	Ikezawa; Atsushi et al.
1	US 6503046 B1	20030107	Apparatus and method for extracting a single bar from a plurality of	414/730	414/745.1; 414/745.5; 414/745.7	Saiki; Akio et al.

			bars			
1	US 6473177 B2	20021029	Particle-size distribution measuring apparatus	356/336	356/335	Yamaguchi; Tetsuji
1	US 6465388 B1	20021015	Process for forming a film with photocatalytic function	502/159	106/287.1; 106/287.19; 427/412.1; 502/158; 502/527.12; 502/527.13	Hozumi; Atsushi et al.
1	US 6454545 B1	20020924	Compressor	417/269	137/856; 137/857; 417/571	Ikeda; Hayato et al.
1	US 6402483 B1	20020611	Double-headed piston compressor	417/269	417/312; 417/540	Kawamura; Hisato et al.
1	US D455037 S	20020402	Case for magnetic disks	D6/632	D3/201; D6/407	Baba; Noriaki
1	US 6364629 B1	20020402	Valve structure with configured retainer	417/269		Shintoku; Noriyuki et al.
1	US 6357340 B1	20020319	Piston compressor piston	92/155	92/248	Kato; Takayuki et al.
1	US 6334977 B1	20020101	Powder material for powder plasma overlaying and powder plasma overlaying metal	420/70	420/34; 75/228; 75/246; 75/255	Matsui; Masakazu et al.
1	US 6296457 B1	20011002	Discharge pulsation damping apparatus for compressor	417/312	181/403; 417/269	Shintoku; Noriyuki et al.
1	US 6293768 B1	20010925	Piston type compressor	417/312	417/269; 92/71	Shintoku; Noriyuki et al.
1	US 6276673 B1	20010821	Fluid-filled active vibration damping device having stabilizing member for	267/140.14		Hibi; Masayuki et al.

			stabilizing oscillating member			
1	US 6250648 B1	20010626	Gasket for sealing a refrigerant compressor	277/652	277/594	Ikeda; Hayato et al.
1	US 6231315 B1	20010515	Compressor having a valve plate and a gasket	417/269	137/856; 417/560	Ikeda; Hayato et al.
1	US 6206351 B1	20010327	Pneumatically operated active vibration damping device having pressure regulating device	267/140.14	267/140.13	Hamada; Masaaki et al.
1	US 6192784 B1	20010227	Swash plate compressor	92/71	92/155	Kato; Takayuki et al.
1	US 6191853 B1	20010220	Apparatus for measuring particle size distribution and method for analyzing particle size distribution	356/336	250/575; 356/337; 356/338	Yamaguchi; Tetsuji et al.
1	US 6186514 B1	20010213	Gasket for sealing a refrigerant compressor	277/594	277/639; 277/644	Ikeda; Hayato et al.
1	US 6068265 A	20000530	Gasket for sealing a refrigerant compressor	277/652	277/594	Ikeda; Hayato et al.
1	US D416548 S	19991116	Connecting device for peripheral equipment of an electronic computer	D14/434		Sugano; Yoshihiko et al.
1	US 5842836 A	19981201	Reciprocating piston type refrigerant	417/269	92/71	Tarutani; Tomoji et al.

			compressor having a housing with enhanced sealing function			
1	US 5839472 A	19981124	Valve mechanism of a compressor	137/856	137/855	Shintoku; Noriyuki et al.
1	US 5809865 A	19980922	Piston-type compressor with reduced vibration	92/71	417/269	Ikeda; Hayato et al.
1	US 5795139 A	19980818	Swash plate type refrigerant compressor with improved internal lubricating system	417/269	184/6.17; 62/470	Ikeda; Hayato et al.
1	US 5603611 A	19970218	Piston type compressor with simple but vibration-reducing suction reed valve mechanism	417/269	137/856; 417/569; 417/571	Tarutani; Tomoji et al.
1	US 5379799 A	19950110	Discharge valve apparatus for compressor	137/856		Kawai; Katsunori et al.
1	US 5282355 A	19940201	Exhaust gas NO.sub.x removal system	60/39.5	60/39.182	Yamaguchi; Tetsuji
1	US 5278413 A	19940111	Infrared microscopic spectrometer	250/347	250/339.07; 250/339.11	Yamaguchi; Tetsuji et al.
1	US 5134463 A	19920728	Stress relief layer providing high thermal conduction for a semiconductor device	257/712	257/677; 257/E21.512; 257/E23.028; 257/E23.109; 257/E23.112; 257/E23.14; 257/E25.016; 361/707; 361/714	Yamaguchi; Tetsuji
1	US 4987390	19910122	Superconducting reversible	332/173	331/187	Mouri; Kaneo et al.

	A		variable inductor			
1	US 4417491 A	19831129	Automatic bar material feeding apparatus	82/126	414/18; 414/746.4; 414/746.7; 82/153	Uehara; Sukehiro et al.